## PATENT ASSIGNMENT

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SUBMISSION TYPE:	NEW ASSIGNMENT
NATURE OF CONVEYANCE:	ASSIGNMENT

### **CONVEYING PARTY DATA**

Name	Execution Date
Youichirou Kaga	09/03/2007
Junichi Watanabe	09/03/2007
Hisayuki Imamura	09/03/2007
Hiromi Kikuchi	09/03/2007

### **RECEIVING PARTY DATA**

Name:	Hitachi Metals, Ltd.
Street Address:	1-2-1, Shibaura, Minato-ku
City:	Tokyo 105-8614
State/Country:	JAPAN

### PROPERTY NUMBERS Total: 1

Property Type	Number
Application Number:	11911794

#### **CORRESPONDENCE DATA**

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ATTORNEY DOCKET NUMBER: 3883-042

NAME OF SUBMITTER: Stephan A. Pendorf

**Total Attachments: 3** 

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PATENT REEL: 020086 FRAME: 0433

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PATENT REEL: 020086 FRAME: 0434

# **ASSIGNMENT**

In consideration of the payment by ASSIGNEE to ASSIGNORS of valuable consideration, receipt whereof is hereby acknowledged, and for other good and valuable consideration,

ASSIGNORS

Youichirou KAGA

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Japan

hereby sell, assign and transfer to

ASSIGNEE

Hitachi Metals, Ltd.

1-2-1, Shibaura, Minato-ku

Tokyo 105-8614

Japan

and the successors, assigns and legal representatives of the ASSIGNEE, the entire right, title and interest for the United States and its territorial possessions, and countries foreign thereto, in and to any and all improvements which are disclosed in the invention entitled "A SILICON NITRIDE SUBSTRATE, A MANUFACTURING METHOD OF THE SILICON NITRIDE SUBSTRATE, A SILICON NITRIDE WIRING BOARD USING THE SILICON NITRIDE SUBSTRATE, AND SEMICONDUCTOR MODULE", and which is

{WP413136;1}

PATENT

REEL: 020086 FRAME: 0435

U.S. Application No. Assignment

Attorney Docket: 3883-042

found in U.S. Patent Application Serial Number

11/911.794

filed October 17, 2007

filed October 19, 2007

filed October 19,

ASSIGNORS hereby covenant that no assignment, sale, agreement or encumbrance has been made or will be made or entered into which would conflict with this Assignment;

ASSIGNORS further covenant that ASSIGNEE will, upon its request, be provided promptly with all pertinent facts and documents relating to said invention and said Letters Patent and legal equivalents as may be known and accessible to ASSIGNORS and will testify as to the same in any interference, litigation or proceeding related thereto and will promptly execute and deliver to ASSIGNEE or its legal representatives any and all papers, instruments or affidavits required to apply for, obtain, maintain, issue or enforce said application,

{WP413136;1}

PATENT REEL: 020086 FRAME: 0436 U.S. Application No. Assignment

3883-042 Attorney Docket:

said invention and said Letters Patent and said equivalents thereof which may be necessary or desirable to carry out the purposes thereof.

Date: September 3, 2007 Date: September 3, 2007

Yourchiron KAGrA Hiromi KIKUCHI Hiromi KIKUCHI

Date: September 3, 2007

Date: September 3 2007

Misayuki IMAMURA

Junichi Watanabe

Junichi WATANABE

(Legalization not required for recording but is prima facie evidence of execution under 35 U.S.C. §261.)

**RECORDED: 11/08/2007**